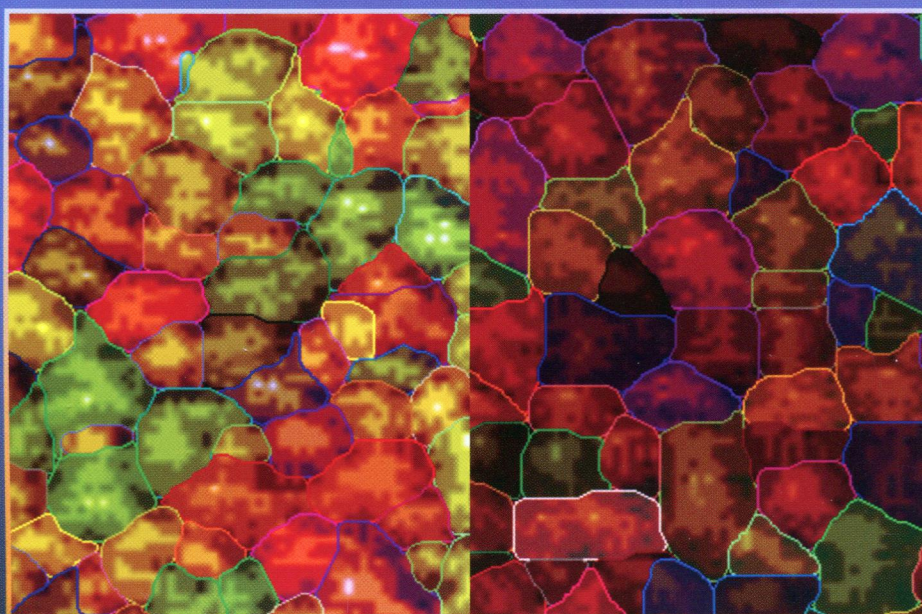


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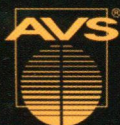
# JVSTA A

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## Vacuum, Surfaces, and Films



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**On The Cover:** *Katherine Knisely and Karl Grosh, JVST A 32(5), p. 051504-1 (2014). Cover shows a comparison of the grain structure of the surface of S-gun sputtered aluminum nitride, deposited by a single deposition (left) and two sequential depositions (right).*